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Sheet 1 of 2

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET
M122-1427SERIAL NO.
Filed HerewithLIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Micron Technology, Inc.FILING DATE
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GROUP

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
JK	AA	4,954,867	09/04/90	Hosaka	257	639	
JK	AB	5,441,797	08/15/95	Hogan et al.	428	209	
JK	AC	5,472,827	12/05/95	Ogawa et al.	430	315	
JK	AD	5,674,356	10/07/97	Nagayama	438	694	
JK	AE	5,710,067	01/20/98	Foot et al.	438	636	
JK	AF	5,731,242	03/24/98	Parat et al.	438	586	
JK	AG	5,741,721	04/21/98	Stevens	438	396	
JK	AH	5,759,755	06/02/98	Park et al.	430	512	
JK	AI	5,838,052	11/17/98	McTeer	257	437	
	AJ						
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FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
JK	AL	JP06067019A	1/92	Japan (Abstract)	-	-		
JK	AM	0 471 185 A2	2/92	EPO	-	-		
JK	AN	0 588 087 A2	3/94	EPO	-	-		
JK	AO	0 588 087 A3	3/94	EPO	-	-		
	AP							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

JK	AR	ARTICLE: Bencher, C. et al., "Dielectric antireflective coatings for DUV lithography", Solid State Technology (March 1997), pp. 109-114.
JK	AS	ARTICLE: Dammel, R. R. et al., "Dependence of Optical Constants of AZ® BARLi™ Bottom Coating on Back Conditions", SPIE Vol. 3049 (1997), pp. 963-973.
JK	AT	TEXT: Heavens, O. S., "Optical Properties of Thin Solid Films", pp. 48-49.

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JK E. E. E.

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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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APPLICANT
Micron Technology, Inc.

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U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA					
	AB					
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FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AL						
	AM						
	AN						
	AO						
	AP						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

9/22	AR	TEXT: Jenkins, F. et al., "Fundamentals of Optics", Properties of Light, pp. 9-10.
9/22	AS	TEXT: Wolf, S. et al., "Silicon Processing for the VLSI Era", Vol. 1, pp. 437-441.
	AT	

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J. E. Eubank

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1427		SERIAL NO. 09/559,903	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Zhiping Yin et al.			
				FILING DATE April 26, 2000		GROUP 2825	
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
9/20/01	AA	App. 09/030,618 as filed and amended	2/25/98	Holscher			02/98
	AB						
	AC						
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FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
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EXAMINER 9/20/01	DATE CONSIDERED 9/20/01
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
ym	AA	5,968,324	10/99	Cheung et al.	204	192.28		
ym	AB	5,872,385	02/99	Taft et al.	257	437		
ym	AC	5,883,011	3 04/99	Lin et al.	438	747		
ym	AD	5,960,289	09/99	Tsui et al.	438	275		
ym	AE	6,020,243	02/00	Wallace et al.	438	287		
	AF							
	AG							
	AH							
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FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
ym	AM	US 99/20029	08/99	PCT Search Report				
ym	AN	US 99/20030	08/99	PCT Search Report				
	AO							
	AP							
	AQ							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
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JK	AA	5,472,829	12/95	Ogawa	430	325	
JK	AB	5,591,566	01/97	Ogawa	430	325	
JK	AC	5,641,607	06/97	Ogawa et al.	430	222.1	
JK	AD	5,648,202	07/97	Ogawa et al.	430	325	
JK	AE	5,677,111	10/97	Ogawa	430	313	
JK	AF	5,670,297	09/97	Ogawa et al.	430	318	
JK	AG	5,698,352	12/97	Ogawa et al.	430	14	
JK	AH	5,831,321	03/98	Nagayama	257	412	
JK	AI	5,034,348	07/91	Hartswick et al.	438	453	
JK	AJ	6,008,124	12/99	Sekiguchi et al.	438	653	
JK	AK	5,340,621	08/94	Matsumoto et al.	422	571	
JK	AL	5,600,165	02/97	Tsukamoto et al.	257	323	
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
JK	AM	0-778496 A2/A3	06/97	EPO			
JK	AN	9-55351	02/97	Japan			
	AO						
	AP						
	AQ						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
JK	AR	McKenzie, D. et al., "New Technology for PACVD", Surface and Coatings Technology 82 (1996), pp. 326-333.					
JK	AS	Shibata, Noburu, "Plasma-Chemical Vapor-Deposited Silicon Oxide/Silicon Oxynitride Double-Layer Antireflective Coating for Solar Cells", Jap. Journ. of Applied Physics, Vol. 30, No. 5, May 1991, pp. 997-1001.					
	AT						
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JK				9/20/97			
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